

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: KIIYOSHI KOMIYAMA, TAKAHIRO SHIMODA and HIROSHI
NISHIKAWA

Application No.:

Confirmation

No:

Filed: January 21, 2004

Group No.: 2812

Examiner Andre C. Stevenson

For: DEVICE AND METHOD FOR MONITORING PROCESS EXHAUST GAS,
SEMICONDUCTOR MANUFACTURING DEVICE, AND SYSTEM AND METHOD FOR
CONTROLLING SEMICONDUCTOR MANUFACTURING DEVICE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

APPLICATION DATA SHEET
37 C.F.R. § 1.76

BIBLIOGRAPHIC DATA

1. Applicant information

First applicant: KIIYOSHI KOMIYAMA
Citizenship: JAPAN
Residence: Nirasaki-shi, Yamanashi, JAPAN

Second applicant: TAKAHIRO SHIMODA
Citizenship: JAPAN
Residence: Nirasaki-shi, Yamanashi, JAPAN

Third applicant: HIROSHI NISHIKAWA
Citizenship: JAPAN
Residence: Nirasaki-shi, Yamanashi, JAPAN

2. Correspondence information

Correspondence for this application should be addressed as follows:

Customer No.: 00909

3. Application information

Title of Invention: DEVICE AND METHOD FOR MONITORING PROCESS EXHAUST GAS,
SEMICONDUCTOR MANUFACTURING DEVICE, AND SYSTEM AND METHOD FOR
CONTROLLING SEMICONDUCTOR MANUFACTURING DEVICE

Docket number assigned to this application: 040258-0307509

Suggested Classification: Class:
Subclass:
Technology Center to which subject matter is assigned:

Total number of drawing sheets: 23

Type of application: Utility

Application is to be published. Suggested drawing figure for publication:

Secrecy order under § 5.2:

This application does not disclose subject matter of an application which is under a secrecy order pursuant to § 5.2.

4. Representative information

The following have a power of attorney or authorization of agent in this application:

Customer No.: 00909 Customer No.: 00909

5. Domestic Priority information

Domestic priority for this application is claimed as follows:

35 U.S.C. § 121:

Application No.: 10/111,481

Filed: April 25, 2002

Status: Issue Fee Paid

Relationship: Parent

Application No.: PCT/JP00/07457

Filed: October 25, 2000

Status: pending

Relationship: parent

6. Foreign priority information

Foreign priority is claimed for this application as follows:

Country: JAPAN

Application No.: 11-303534

Filing Date: October 26, 1999

Status: pending

Country: JAPAN

Application No.: 2000-297203

Filing Date: September 28, 2000

Status: pending

7. Assignee information

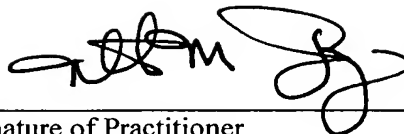
The assignee(s) of this application is/are:

Tokyo Electron Limited
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Extent of interest of assignee in application: 100%

Date: January 21, 2004

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